



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

#27
Amclt
H
8/14/03
aey

Application Serial No. 09/212,726
 Filing Date December 15, 1998
 Inventor..... Klaus F. Schuegraf
 Assignee..... Micron Technology, Inc.
 Group Art Unit..... 2813
 Examiner Kielin, Erik J.
 Attorney's Docket No. MI22-1098
 Title: Semiconductor Processing Methods of Chemical Vapor Depositing SiO₂ on a Substrate

RESPONSE TO APRIL 28, 2003 OFFICE ACTION

To: Mail Stop Non-Fee Amendment
 Commissioner for Patents
 P.O. Box 1450
 Alexandria, VA 22313-1450

From: Jennifer J. Taylor, Ph.D. (Tel. 509-624-4276; Fax 509-838-3424)
 Wells St. John P.S.
 601 W. First Avenue, Suite 1300
 Spokane, WA 99201-3828

RECEIVED
 TECHNOLOGY CENTER 2800
 AUG -1 2003

AMENDMENTSIntroductory Comments

In reply to the office action dated April 28, 2003, applicant amends and remarks as follows.